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INFORMATION DISCLOSURE STATEMENT BY APPLICANT	TNCR.169US2	10/729,609
	Applicant(s)	Conf. No.
(Use several sheets if necessary)	Thomas McWaid	2888
	Filing Date	Group
	December 5, 2003	2856

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*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
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	2	2,728,222	Dec., 1955	Becker et al.	—	—	
	3	3,283,568	Nov., 1966	Reason	—	—	
	4	4,103,542	Aug., 1978	Wheeler et al.	—	—	
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	6	4,441,177	Apr., 1984	Groh et al.	—	—	
	7	4,574,625	Mar., 1986	Olasz et al.	—	—	
	8	4,641,773	Feb., 1987	Morino et al.	—	—	
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DR	44	2009409	Jun., 1979	GB	73	105		
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DR	48	05920	Feb. 1998	WO.	73	105		

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